Atty. Docket: 29926/39496
Title: Batch Type Atomic Layer Deposition
Apparatus and In-Situ Cleaning Method Thereof

Inventor: Hyug-Jin Kwon Sheet 1 of 6 (figs. 1 & 2)

FIG. 1 (PRIOR ART)

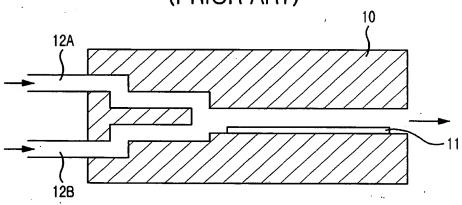
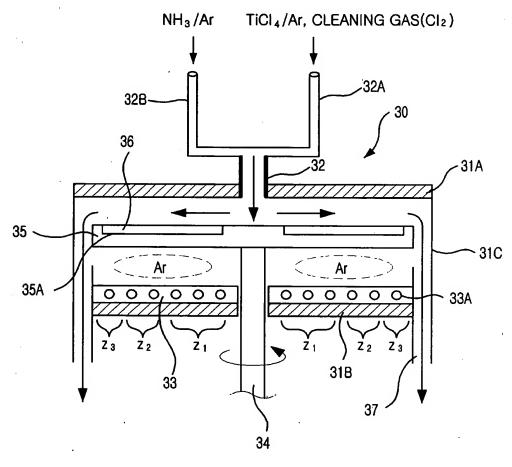


FIG. 2 (PRIOR ART)



Atty. Docket: 29926/39496
Title: Batch Type Atomic Layer Deposition
Apparatus and In-Situ Cleaning Method Thereof

Inventor: Hyug-Jin Kwon Sheet 2 of 6 (figs. 3A & 3B)

FIG. 3A (PRIOR ART)

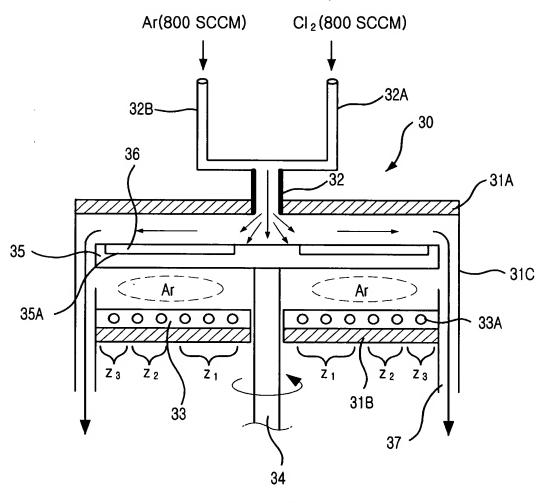
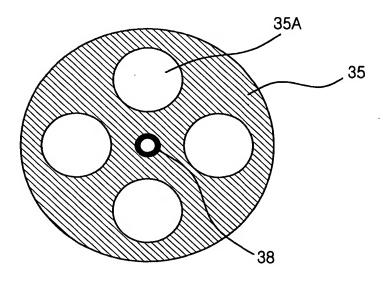


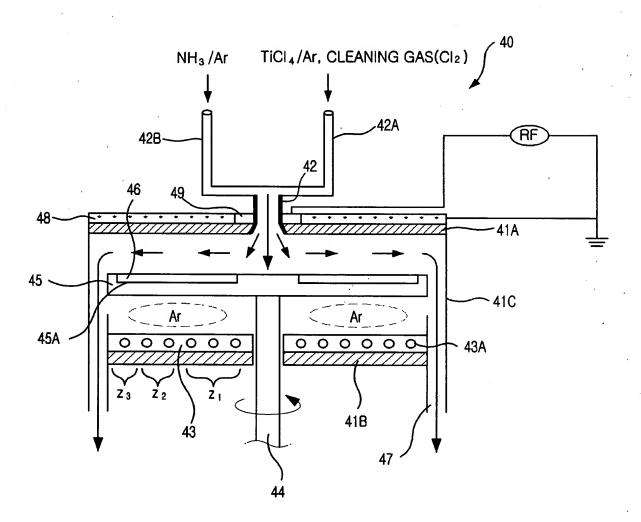
FIG. 3B (PRIOR ART)



Atty. Docket: 29926/39496
Title: Batch Type Atomic Layer Deposition
Apparatus and In-Situ Cleaning Method Thereof

Inventor: Hyug-Jin Kwon Sheet 3 of 6 (fig. 4)

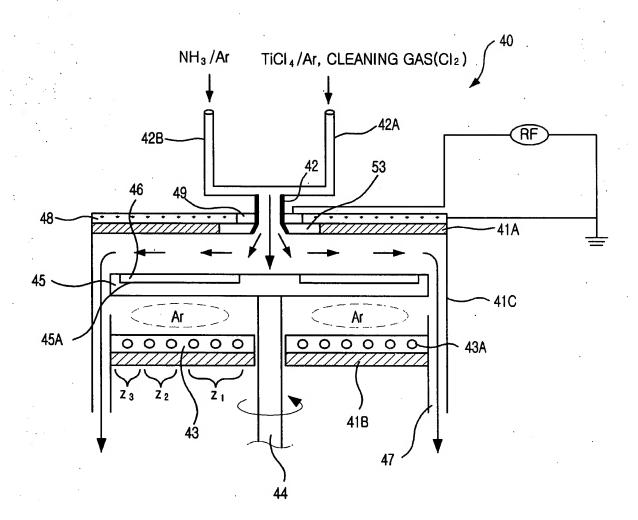
FIG. 4



Atty. Docket: 29926/39496
Title: Batch Type Atomic Layer Deposition
Apparatus and In-Situ Cleaning Method Thereof
Inventor: Hyug-Jin Kwon

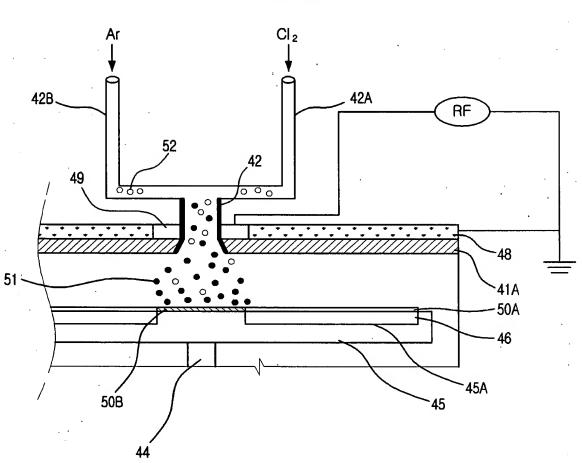
Sheet 4 of 6 (fig. 5)

FIG. 5



Atty. Docket: 29926/39496
Title: Batch Type Atomic Layer Deposition
Apparatus and In-Situ Cleaning Method Thereof
Inventor: Hyug-Jin Kwon
Sheet 5 of 6 (fig. 6)

FIG. 6



Atty. Docket: 29926/39496
Title: Batch Type Atomic Layer Deposition
Apparatus and In-Situ Cleaning Method Thereof
Inventor: Hyug-Jin Kwon
Sheet 6 of 6 (fig. 7)

FIG. 7

